# **Wavefront Analysis by Shadow Raytracing Program**

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### Introduction

- Wavefront sensing is a useful method to measure and correct wavefront imperfection in diffraction limited sources
- Variety of methods, including the knife-edge imaging technique developed at Diamond light source, have been used for wavefront sensing
- □ Here, a simulation method is developed based on the knife-edge technique to:
  - Investigate wavefront error of a specific focusing optics
  - Design of the wavefront corrector
  - Help in optical layout design with minimum wavefront distortion, etc

## Knife-edge Imaging Technique

- □ To step an absorbing knife-edge into the beam while measuring the transmitted intensity on a 2D x-ray detector positioned downstream [2]
- □ The technique has been successfully applied for the wavefront measurement & alignment of a KB mirror, correction of wavefront error by refractive correctors [1], and recently to optimize the wavefront of X-ray Alvarez lens [2]



Schematic layout: Focusing optics, knife-edge, and 2D pixel detector



**Wavefront calculation**: The measured intensity on pixel P2 is projected back to obtain wavefront angular distortion of  $y'_1$ 

### Verification of the Method

- The calculated wavefront matches well with the measured data obtained on B16 beamline at Diamond
- Zero-coma line of the KB grazing angle and shearing of Alvarez lens has been experimentally verified [2]

#### **Raytracing Method**

- □ Setup the beamline/experiment (source, focusing optics, knife-edge, detector) in Shadow (OASYS) [3]
- Calculate the Intensity histogram on a downstream pixel-detector
- □ Scan the knife-edge through the focal spot & finding the edge
- □ Calculate the wavefront error and its polynomial coefficients [1] by additional developed program in OASYS



Beamline layout: wavefront calculation by knife-edge technique for KB mirror (Top); combined KB & wavefront corrector (Middle); combined KB & Alvarez lens (Bottom)



*Intensity histogram*: knife-edge scans for a sinusoidal (Left) and higher frequency (Right) height error profile of an elliptical mirror

#### Advantages

- > Quick way of the wavefront analysis for a variety of focusing optics
- Design and prediction of the wavefront correction by a refractor structure
- Optimize the experimental setup parameters to minimize the coma aberrations
- Save considerably on the experiment time and efforts, and useful for automatic alignment of the focusing optics

### **Outcome & Applications**

- > To optimize the beamline layout by minimizing the parabolic, cubic and residual RMS wavefront error for a focusing optics
- > To design a specific/generic refractor corrector for minimizing the wavefront error in the diffraction limited condition
- > To correct the parabolic and coma aberrations of the x-ray Alvarez lens by adjusting the mirror pitch angle and Alvarez shearing [2]



Focal profile: Parabolic & cubic corrections for x-ay Alvarez lens give free-aberration vertical focal profile (Middle plot)

### References

[1] Adaptable refractive correctors for X-ray optics; D. Laundy, V. Dhamgaye, T. Moxham, & K. Sawhney, Optica 6, 1484 (2019).
[2] An Alvarez varifocal X-ray lens; V. Dhamgaye, D. Laundy, H. Khosroabadi, T. Moxham, S. Baldock, O. Fox, and K. Sawhney, Nature Com. 14, 4582 (2023).

[3] OASYS: A software for beamline simulations and synchrotron virtual experiments; M. Sanchez-del Rio, and L. Rebuffi, AIP Conf. Proc. 2054, 060081 (2019).

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